# Onpria **A NUMERIC MODEL FOR THE IMAGING MECHANISM OFMETAL OXIDE EUV RESISTS**

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### **Negative Tone Resist Chemistries in Organic Polymers**

Direct crosslinking of polymer [poly(4-Cl-styrene)]



Polarity change [t-BOC, NTD resists]



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Chain polymerization [Riston, SU-8]







**None of these describe the primary imaging mechanism in MOx resists**pria

### **A Generic Imaging Model for MOx Resist Systems**

- Basic approach :
	- –Minimalist description of chemistry and physics
	- –Follow progression of radiation and condensation chemistry
- Resist building block notation
	- Core molecule / framework / cluster / nanoparticle
	- **Multiple <b>radiation-sensitive ligands L** per core
	- −Condensation of **active site A** formed upon ligand radiolysis **leads to <mark>Oxo-Network</mark> formation**





# **Analogue of Sol-Gel Process**

- **Characteristics of sol-gel chemistry:**
	- –Site activation by catalyst
	- –Simultaneous condensation and further activation
	- Complex mixture of intermediate species
	- – Polymerization proceeds toward oxo-network formation
- **MOx imaging model:**
	- –Site activation by radiation chemistry
	- –Solid phase condensation of neighboring cores
	- Complex mixture of intermediate species
	- – Polymerization proceeds toward oxo-network formation





### **Overview of Modeling Process**

#### **A Molecular-Scale Description**

- 3D array of individual molecules
- $\textcolor{red}{\bullet}$  Track individual events
- Statistical effects accounted for

#### **Model Inputs**:

- Molecular volume
- Number of radiation-sensitive ligands per core
- EUV absorption coefficient
- П "Quantum yield":
- –Definition: **number of ligands fragmented per photon absorbed**
- In model, use the number of electrons generated per photon as a proxy
- п "Radiochemical blur length":
- – Definition: **distance scale over which chemical change may occurfrom point of photon absorption**
- In model, use "electron blur" length as a proxy–
- Film thickness
- Exposure dose





# **Step 1 - EUV Absorption**

#### **A stochastic implementation of Beer's Law**

#### **Protocol:**

- $\blacksquare$ Divide film surface into sub-areas
- $\blacksquare$ Distribute impinging photons onto surface
- $\blacksquare$  Distribute photons in sublayers according to probabilities

#### **Example**

- molecular volume 2.3 nm<sup>3</sup>
- 15 mJ/cm<sup>2</sup> flood exposure ■
- **1928 impinging photons, 662 absorbed** ■





### **Step 2 - Secondary Electron Generation**

**Apply experimentally derived electron yield and blur length to photon absorption distribution** 

### **Protocol:**

- Each photon generates on average *n* electrons
- $\blacksquare$  Allow electrons to stochastically "diffuse" from point of photon absorption
- $\blacksquare$  Terminate electron diffusion when average diffusion distance = blur length

#### **Example**

- molecular volume 2.3 nm<sup>3</sup>  $\blacksquare$
- 15 mJ/cm<sup>2</sup> flood exposure
- avg 8 electrons per photon ■
- 1.4 nm electron blur length





### **Step 3 – Primary Photoproduct Distribution**

- $\blacksquare$ Allow electron distribution to interact with resist material
- $\blacksquare$  Assumptions:
	- **Links of the Company** Each ligand is chemically equivalent
	- **Links of the Company** Reactivity is unaffected by degree of decomposition
- A complex product mix results: e.g., for a tetra-substituted core



Photoproduct distribution is a function of dose



### **An Example Photoproduct Spatial Distribution**

Hypothetical MOx resist with 12 radiation-sensitive ligands per core, EUV flood exposure 15 mJ/cm2 dose





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#### **Photoproduct Distribution Depends on Dose**



### **Impact of Photoproduct Distribution**

Role of photoproduct in condensation depends on structure:





#### **Photoproduct Distribution Depends on Dose**



# **Step 4 – Condensation of Primary Photoproducts**

- Calculate the evolution of oxo-networks
	- Each core starts with a set number of active sites
	- Condensation only if core and neighbor both have an active site
	- Condensation forms one oxo-bond and consumes two active sites
- Protocol:
	- a) Initialize with photoproduct distribution
	- b) Select a core
	- c) Core and neighbor both have active sites?
		- i. Form oxo-bond
		- ii. Subtract active sites
	- d) Repeat (b) and (c) until probability of reaction is zero

#### **Result: Population of oxo-network polymers**







# **Step 5 – Analyze Topology of Condensation Products**

# Protocol:

- a) Scan through array of cores looking for bonds
- b) If a core is bonded to any of its neighbors
	- 1. Check each bonded neighbor to see if it is bonded to its neighbors
	- 2. Recursively following the bonding including branches and crosslinks
- c) Continue scan until every core has been visited



### **Result: 3D map and population distribution of oxo-network polymers**



### **Condensation Product Distribution vs Dose**



### **Calculate Resist Contrast for a Real Resist**

#### **Inpria experimental MOx resist system**

- 1. Estimate quantum yield and blur length from experimental data
- 2. Use model to calculate condensation products vs dose
- 3. Apply binary dissolution process
	- – Only condensation products in direct contact with the substrate are insoluble



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#### **Imaging - Chemical Latent Images NXE 3300, Dipole illumination, 16 nm line/32 nm pitch**



#### 20 mJ/cm2







15  $mJ/cm<sup>2</sup>$ 

# **Calculated Line-Space Images**

#### **NXE 3300, Dipole illumination, 16 nm line/32 nm pitch**







### **Calculated vs Experimental Image : 24 nm pitch**



#### Imaged using EUV-IL tool(Paul Scherrer Institut)



# **Summary**

#### **Simple chemical description of MOx resist**

Photo-induced condensation of **multifunctional** cluster

EUV exposure chemistry data from **Inpria MOx resist** test vehicles

General **stochastic simulation** process

#### **Quantitative link between photochemistry and imaging**

Contrast originates from non-linear **oxo-network** formation

**Lithographic predictions** consistent with experimental observations

Potentially applicable to **many resist systems** 

